

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

Inventor(s): Jeffrey W. Carr

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Title: Apparatus and Method for Reactive Atom
Plasma Processing for Material Disposition

PATENT APPLICATION

Art Unit: 1765

Examiner: Lan Vinh

Customer No. 23910

**INFORMATION DISCLOSURE STATEMENT AFTER NOTICE OF ALLOWANCE
PURSUANT TO 37 C.F.R. §1.97(i)**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicant is filing this Information Disclosure Statement (IDS), after receipt of the Notice of Allowance mailed August 6, 2007, for the above-captioned application. The patents/patent publication documents and non-patent documents listed in the IDS were recently cited by the Office in other patent applications for the same client.

This filing is not intended to represent that the references cited herein are material to patentability as defined in 37 C.F.R. §1.56. Rather, Applicant does not believe that they affect the patentability of the allowed claims in the above-captioned application. Applicant offers that the references are being submitted to satisfy the duty of disclosure.

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Applicant respectfully requests that this IDS and these references be placed in the application file.

No fee is believed due in connection with this paper. However, the Commissioner is authorized to charge any underpayment or credit any overpayment to Deposit Account No. 06-1325 for any matter in connection with this filing, including any fee for extension of time, which may be required.

Respectfully submitted,

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